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2019

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Torretti, F. (2019). *Spectroscopy of highly-charged Sn ions for extreme ultraviolet nanolithography*. [PhD-Thesis - Research and graduation internal, Vrije Universiteit Amsterdam].

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CONTENTS

List of Figures	vii
List of Tables	ix
Introduction	1
1 Analysis of the fine structure of Sn¹¹⁺–Sn¹⁴⁺ ions by optical spectroscopy in an electron beam ion trap	9
1.1 Introduction	10
1.2 Experiment	12
1.3 Theory	13
1.4 Results	16
1.5 Conclusions	29
2 Optical spectroscopy of complex open-4<i>d</i>-shell ions Sn⁷⁺–Sn¹⁰⁺	31
2.1 Introduction	32
2.2 Experiment	33
2.3 Theory	34
2.4 Results	40
2.5 Conclusions	52
2.6 Acknowledgments	53
2.7 Appendix	53
3 Short-wavelength out-of-band euv emission from Sn laser-produced plasma	63
3.1 Introduction	64
3.2 Experiment	65
3.3 Calculations	67
3.4 Comparison	71

3.5	UTA formalism	74
3.6	Spectral shape parameters	75
3.7	Conclusions	78
3.8	Acknowledgments	79
4	Spectral characterization of an industrial EUV light source for nano-lithography	81
4.1	Introduction	82
4.2	Experiment	82
4.3	Results	86
4.4	Conclusions	91
4.5	Acknowledgments	92
5	Radiation transport and scaling of optical depth in Nd:YAG laser-produced microdroplet-tin plasma	95
5.1	Introduction	96
5.2	Experiment	97
5.3	Methods	98
5.4	Results	100
5.5	Conclusions	104
5.6	Acknowledgments	104
6	Unexpectedly large radiative emission between highly-excited states in Sn laser-produced plasma	107
6.1	Introduction	108
6.2	Atomic structure calculations	108
6.3	Comparison	113
6.4	Discussion and conclusions	116
6.5	Acknowledgments	117
6.6	Appendix	117
A	Opacity and emissivity in LTE	123
	References	127
	List of publications	145
	Acknowledgments	149